

## ABSTRACT OF THE DISCLOSURE

A control unit, which divides a controlled system into a plurality of zones and carries out control of the individual  
5 zones separately, can match the timings for the zones to reach a steady-state reference temperature by basic control. It can effectively reduce overshoot and undershoot after reaching the steady-state reference temperature, and suitably control the temperature of a wafer in the fabrication process of semiconductor  
10 devices.